CLAIMS

- 1-12. (Canceled)
- 13. (Currently amended) A method of fabricating a dielectric material, said method comprising: incorporating a Group V element in a Group III metal oxide, wherein said dielectric material is deposited in an atmosphere comprising a mixture of oxygen and nitrogen <u>having an oxygen-to-nitrogen ratio</u> ranging from about 24:6 to about 18:12.
- 14. (Original) A method according to claim 13, wherein said Group III metal oxide is aluminum oxide.
- 15. (Original) A method according to claim 13, wherein said Group V element is selected from the group consisting of nitrogen and phosphorous.
- 16. (Original) A method according to claim 14, wherein said Group V element is selected from the group consisting of nitrogen and phosphorous.
 - 17-18. (Canceled)
- 19. (Previously presented) A method according to claim 13, wherein said mixture of oxygen and nitrogen has an oxygen-to-nitrogen ratio of about 18:12.
 - 20. (Canceled)
- 21. (Original) A method according to claim 13, wherein said dielectric material is formed by a technique selected from the group consisting of reactive sputtering, annealing, atomic layer deposition (ALD), chemical vapor deposition (CVD), metalorganic chemical vapor deposition (MOCVD), plasma nitridation, and oxidation of metal nitrides.
 - 22-26. (Canceled)
- 27. (Previously presented) A method according to claim 13, comprising forming the dielectric material on a substrate using the oxygen and the nitrogen from said atmosphere.
- 28. (Currently amended) A method according to claim 16, wherein: said mixture of oxygen and nitrogen has an oxygen-to-nitrogen ratio ranging from about 24:6 to about 9:21;

said dielectric material is formed by a technique selected from the group consisting of reactive sputtering, annealing, atomic layer deposition (ALD), chemical vapor deposition (CVD), metalorganic chemical vapor deposition (MOCVD), plasma nitridation, and oxidation of metal nitrides; and

the method comprises the step of forming the dielectric material on a substrate using the oxygen and the nitrogen from said atmosphere.

29. (Previously presented) A method according to claim 28, wherein said mixture of oxygen and nitrogen has an oxygen-to-nitrogen ratio of about 18:12.

30-31. (Canceled)